



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Applicant:

Ofer DU-NOUR

Serial No.: 09/762,473

Filed: February 7, 2001

Group Art Unit: 2877

For: Method and Apparatus for Measuring the  
Thickness of a Transparent Film,  
Particularly of a Photoresist Film on a  
Semiconductor Substrate

Attorney  
Docket: 24982  
Previously 1639/14

Examiner: Samuel A. Turner

**RESPONSE**

Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

Sir:

This is in response to the United States Patent and Trademark Office Action mailed September 2, 2003, which response is being made on or before March 2, 2004 and for which a three-month extension fee is due and is being submitted herewith.

Please amend the above-identified patent application as follows:

**In the Drawings:**

Permission is requested to correct Figs. 1a, 1b and 2 as shown in red ink on the attached photocopies.